

ECSEL Way2GoFast project

- UTBB FDSOI technology applications expand from Digital to mixed Digital-Analog-RF-mmW circuits
 - Market segments include Automotive, Connectivity, IoT, ...
- Device Figures-of-merits (FoMs) addressed are multiple
 - Energy consumption remains as driving design parameter
 - Digital: Low dynamic power at given frequency, Low static power
 - Analog: Analog Gain, Variability (Matching, SCE), at low current
 - RF-mmW: High frequency response preserved at low voltage/low current
- Within ECSEL Way2GoFast project, during 2015 2017, 2 important developments were conducted in order to extend 28nm FDSOI technology applications to Low Power Digital-Analog-RF
 - · Statistical Variability analysis, in cooperation with SYNOPSYS
 - · Leti-UTSOI model enhancement for Low Power, in cooperation with CEA Leti



SUPERAID7 Workshop "Process Variations from Equipment Effects to Circuit and Design Impacts" September 3, 2018, Dresden

A.Juge & al. Statistical Variability analysis in 28nm FDSOI devices





Ultra-Thin Buried oxide

Variability Impact on Low Power Circuit Design



- SV experiments in UTBB FDSOI
- Reduced Vdd or Id for Low Power
- Implies Near-Threshold operation
- SV impact x 3 from upper limit to lower limit of moderate inversion
- Objectives:
 - · Device variability analysis
 - Model accuracy for circuit design throughout voltage range



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Outline

Presentation

Introduction to project Way2GoFast

Statistical Variability analysis in 28nm FDSO Characterization (Physical - Electrical)

TCAD device calibration (Physical - Electrical) GARAND device calibration Variability simulation with GARAND Device analysis

Model for Circuit Design

Summary

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SYNOPSYS

Silicon to Software

MGG

augme

LER

SV Characterization: Approach

- Objective
 - · To rely on most complete and consistent data set
 - Physical and Electrical characterization techniques
- Physical
 - Line Width/Edge Roughness (LWR/LER)
 - Metal Grain Granularity (MGG). Grain size & Orientation.
 - Body Thickness Variation (BTV)
 - Some unknowns remain
 - Random Discrete Dopants (RDD) -> Discrete profile determined by Garand from calibrated continuous doping profiles
 - MGG work-function values -> calibrated through variability simulation process
 - Statistical impact of trapped charges at the interfaces of the thin body channel

Electrical

• I(V) data from transistor array (256 pairs of DUT distributed in one direction), 1 die



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Gife Control Una Thin Buried oxide by Garand from

BTV

Identification of median DUT



Sentaurus Device calibration: Electrostatic



Sentaurus Device Calibration: Transport





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Statistical Variability analysis in 28nm FDSO

Characterization (Physical - Electrical) TCAD device calibration (Physical - Electrical) **Garand device calibration** Variability simulation with Garand Device analysis

Model for Circuit Design

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SYNOPS

Silicon to Software

augr

Simulation with Garand

- Device structure
 - Sentaurus 2D structure extended to 3D
 - · Mesh refinement for regions (interfaces) exposed to LER and BTV
- Calibration strategy
 - Reference data: Device simulations from Sentaurus
 - Calibration Targets for Enigma tool
 - Charge distribution at middle of channel (density gradient DG)
 - Inversion charge Ninv vs Vgate voltage
 - · Id (Vgate) at low and high Vd voltage for mobility fitting
 - Verification Cgg vs Vgate



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Device structure 13





- Short gate length device extruded to 3D (left)
- Mesh refinement for regions exposed to LER and BTV (right)



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SAUDLSAZ

Silicon to Software



Created Automated Garand Calibration flow for FDSOI technologies





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Electrical inputs for Garand calibration ____



Local Variability inputs for Garand

Source	Parameter	comment	
RDD	Supplied profile	Discretization by Garand	6e - 09
MGG	Average grain diameter	TEM data	$_{4e-09}$ Uncorrelated axis
	Orientation probability	TEM data	2e - 09
	Orientation Wf_delta	Literature for <111> & <200>, otherwise adjusted	
LER	RMS	LER data	-2e - 09
	LCOR	Best-guess	-4e-09
BTV	RMS	DRM/AFM data + adjust.	$-6e - 09 \begin{bmatrix} \bullet & \bullet \\ -6e - 09 - 4e - 09 - 2e - 09 & 0.0 & 2e - 09 & 4e - 09 & 6e - 09 \end{bmatrix}$
	LCOR	Best-guess	ler_l

Unknown parameters updated through iterative variability simulation (3-4)

• Enigma had to manage 2000 statistical simulations per iteration



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Statistical Variability Analysis (nMOS)







Simulation/Hardware FOMs variations and correlations (normalized)

Sources contribution	σVT_{LIN}	σVT_{SAT}	σDIBL	σ ION _{LIN}	σ ION _{SAT}
RDD	3	3	3	1	2
LER	4	4	3	4	4
MGG	1	1	2	3	1
BTV	2	2	1	2	3



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How gm/I accuracy serves statistical model accuracy? Leti UTSOI enhancements for gm/I

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How Gm/Id model accuracy serves statistical modeling?



Strong inversion

$$Ids \propto \beta \times (Vgs - Vth - Dibl \times Vds)^{a}$$

$$\left(\frac{\sigma_{Ids}}{Ids}\right)^2 = \left(\frac{\sigma_{\beta}}{\beta}\right)^2 + \left(\frac{gm}{Ids}\right)^2 \times [\sigma_{Vth}^2 + Vds \times \sigma_{Dibl}^2]$$

SYNOPSYS

Silicon to Software

augme

- Gm/Id is the amplification factor by which variability in electrostatics induces biasdependent variability of current
- Applies for whatever inversion regime
- Gm/Id accuracy helps variations modeling

Weak inversion

SDE

 $Ids \propto \beta \times \exp (Vgs - Vth - Dibl \times Vds) / (n \times ut))$

$$\left(\frac{\sigma_{Ids}}{Ids}\right)^2 = \left(\frac{\sigma_{\beta}}{\beta}\right)^2 + \left(\frac{gm}{Ids}\right)^2 \times \left[\sigma_{Vth}^2 + Vds^2 \times \sigma_{Dibl}^2 + (Vgs - Vth)^2 \times \left(\frac{\sigma_n}{n}\right)^2\right]$$



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[SISPAD 2016]



Leti UTSOI model enhancement for Gm/I 21

Mobility and series resistance model improvements



Leti UTSOI model enhancement for Gm/I

Improvement of accuracy in moderate inversion region



Summary 23

- Modelling for Low Power Analog-RF in 28nm FDSOI technology highlighted
 - Support of ECSEL JU Way2GoFast project
 - Cooperation between CEA Leti, Synopsys, and ST
- Physical/Electrical characterization methodologies suited for FDSOI devices
 - Some unknown parameters remain (Work-function values per grain orientation)
- Variability analysis with Garand
 - Provided well-calibrated TCAD deck, and set of physical/electrical variability data, Garand can
 predict the local variability, including key figure of merit sigmas and correlations
 - Tool chain capabilities were extended (MGG,..).
 - Enigma provides capability of reverse-engineering to provide physical inputs not available
 - Calibration methodology ensures consistent variability inputs for nMOS and pMOS devices
 - Comprehensive analysis of statistical variability observed in 28nm FDSOI device characteristics
 - · Classification of local variability sources provides guidance for LP device optimization

Leti-UTSOI model for Low Power Circuit Design

- · Accuracy in Gm/Id metric is valuable for Variability modeling
- Leti-UTSOI qualified for Low Power Analog-RF circuit design using 28nm FDSOI technology



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